



GP 1763

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: YOUNG-HOON PARK)
SERIAL NUMBER: 09/848,577) Group Art Unit:
FILED: May 3, 2001) 1763
FOR: REACTOR FOR DEPOSITING) Examiner:
THIN FILM ON WAFER) Karlaa Moore.

17.B
12/19/02
MW

RECEIVED

Commissioner of Patents and Trademarks
Washington, D.C. 20231

DEC 17 2002

TC 1700

Dear Sir:

This amendment with remarks is submitted in response to an Office Action dated September 11, 2002. Applicant requests reconsideration of the outstanding rejection in view of the following remarks and amendments.

AMENDMENT

I HEREBY CERTIFY THAT THIS CORRESPONDENCE
IS BEING DEPOSITED WITH THE UNITED STATES
POSTAL SERVICE AS FIRST CLASS MAIL IN AN
ENVELOPE ADDRESSED TO:
ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

ON 09 DEC. 2002 DATE OF DEPOSIT

Daniel Drexler (TYPED OR PRINTED NAME OF PERSON MAILING PAPER OR FEE)

SANDY 09 DEC. '02 SIGNATURE DATE

IN THE CLAIMS:

Please enter the following newly added claims.

18. (Newly Added) The thin film deposition reactor of claim 1, wherein an interval between a center of the diffusion plate and the wafer block is different from an interval between edges of the diffusion plate and the wafer block.

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